

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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| Application No. | : (To Be Assigned) | Confirmation No. | : (TBA) |
| | PCT/JP2004/009026 | | |
| First Named Inventor | : Hiroshi KANNAN | | |
| Filed | : December 27, 2005 | | |
| TC/A.U. | : (To Be Assigned) | | |
| Examiner | : (To Be Assigned) | | |
| Docket No. | : 010986.57272US | | |
| Customer No. | : 23911 | | |
| Title | : Plasma Generation Method, Cleaning Method, and Substrate Processing Method | | |

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Please enter the following amendments to the specification and claims, as amended by way of Annexes to the International Preliminary Examination Report for PCT/JP2004/009026, prior to the examination of the application during the U.S. National Phase.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 22 of this paper.